## IN THE CLAIMS

- 1. (Currently Amended) An assembly, comprising:
- a heater to pre-heat an entire substrate and an entire embossable film, disposed above the a substrate, to an approximate embossing temperature;
- a die assembly having an embossing foil to imprint the embossable film; and a heat tunnel disposed between the heater and the die assembly to maintain the approximate embossing temperature.
- 2. (Original) The assembly of claim 1, further comprising a transporting device for the substrate.
- 3. (Original) The assembly of claim 2, wherein the transporting device comprises a vacuum chuck coupled to a robotic arm.
- 4. (Original) The assembly of claim 2, wherein the transporting device comprises a servo slide.
- 5. (Currently Amended) The assembly of claim 4, wherein the servo slide comprises:
  - a frame;
  - a holder plate to receive the disk substrate; and
- at least two fingers to secure the substrate within the holder plate, the at least two fingers to maintain a precise position of the substrate.
- 6. (Previously Presented) The assembly of claim 1, wherein the die assembly comprises:
- an elongated shaft with a tapered mandrel end portion to receive the substrate having a hole defined by an inner dimension edge of the substrate;

-2-

a ball bushing disposed around the elongated shaft; and

a ring portion disposed between the ball bushing and the embossing foil, wherein the ball bushing has a thermal expansion to enable the ball bushing to expand and secure the ring portion to the embossing foil and to align a centerline of the embossing foil with a centerline of the substrate.

- 7. (Original) The assembly of claim 1, further comprising an gas actuation bladder coupled to the die assembly.
- 8. (Original) The assembly of claim 1, further comprising a vision device to inspect an imprint pattern on the substrate.
- 9. (Original) The assembly of claim 1, further comprising a cooling station disposed near the die assembly.
- 10. (Original) The assembly of claim 1, wherein the die assembly is used to imprint the embossable film for production of an optical recording disk.
- 11. (Original) The assembly of claim 1, wherein the die assembly is used to imprint the embossable film for production of a semiconductor device.
- 12. (Original) The assembly of claim 1, wherein the heat tunnel comprises an inductive heat tunnel.
- 13. (Original) The assembly of claim 1, wherein the heat tunnel comprises an IR heat tunnel.
- 14. (Original) The assembly of claim 1, wherein the substrate comprises a disk.

Claims 15 – 26 (Canceled)

27. (Currently Amended) An assembly, comprising:

means for pre-heating <u>an entire substrate and</u> an <u>entire</u> embossable film, disposed above <u>the</u> a substrate, to an approximate embossing temperature; and

means for transporting the substrate to an imprinting die assembly, having an embossing foil, while maintaining the approximate embossing temperature.

- 28. (Original) The assembly of claim 27, further comprising:
  means for centering the substrate relative to an embossing foil disposed within the imprinting die set.
- 29. (Original) The assembly of claim 27, further comprising means for inspecting an embossed pattern on the embossable film.
- 30. (Original) The assembly of claim 27, further comprising means for cooling the substrate.